

# Deposition Control and Depth Profiling in TaOx Memristors

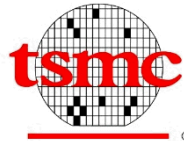
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Barney L. Doyle, Michael T. Brumbach,  
Matthew J. Marinella

# What are Memristors

## Resistive Memory

- Flash has reached its limit
  - What's next?

**Panasonic**  
ideas for life



**TOSHIBA**  
Leading Innovation >>>



**ELPIDA**

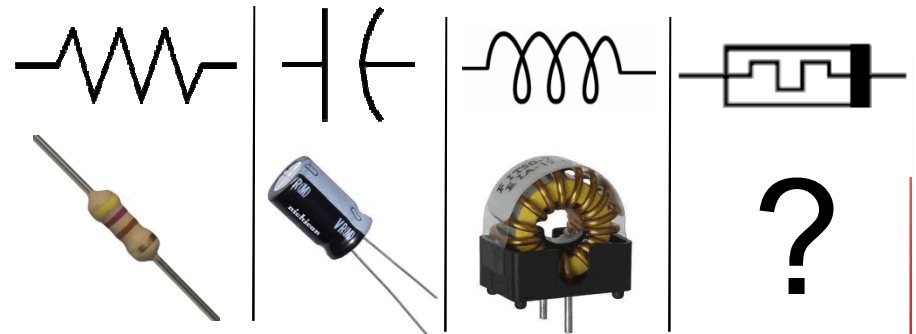
**hynix**

**SanDisk**



## Novel Circuit Element

- Leon Chua in the 70's
  - Resistor, Capacitor, Inductor, ?



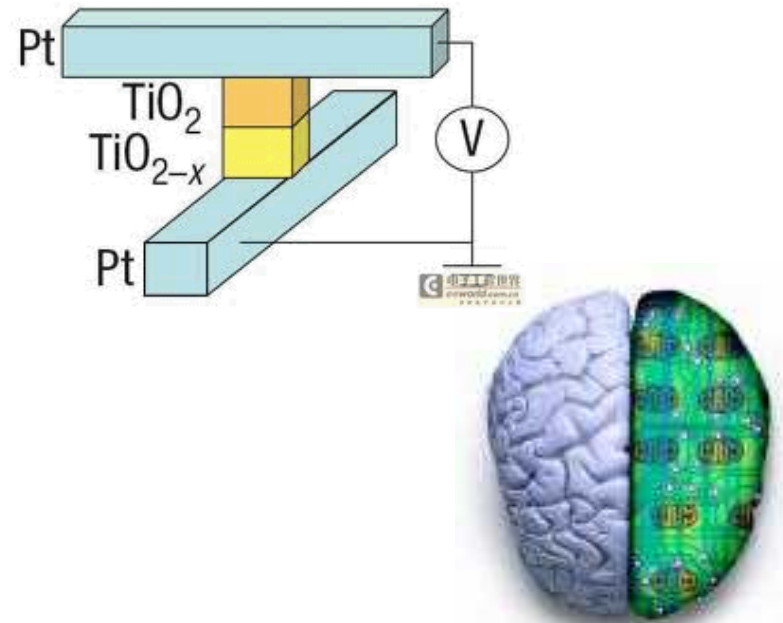
# What are Memristors

## Resistive Memory

- Performance in TaOx?
  - 30 nm (and shrinking)
  - Sub nanosecond switching
  - >10 year retention
  - ~10 pJ switching energy
  - CMOS compatible
  - Multi-level cell
  - 3D stackable
  - Simple architecture
- Remaining Issues?
  - Continued Scaling and Integration
  - Process Uniformity/Reproducibility
  - Forming Process
  - Nonlinearity

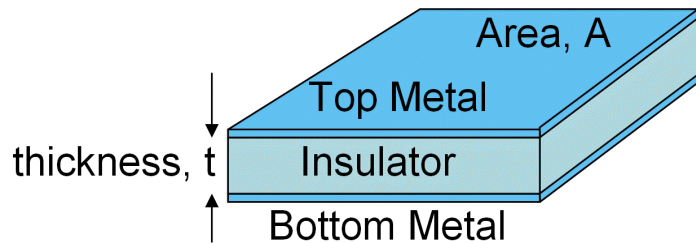
## Novel Circuit Element

- HP in 2008 Showed One
  - Nanoscale TiO<sub>2</sub> is a memristor

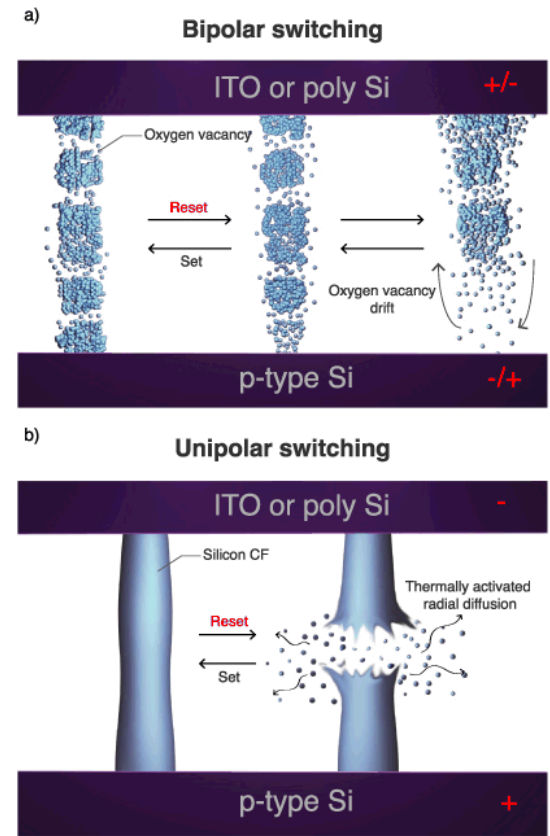
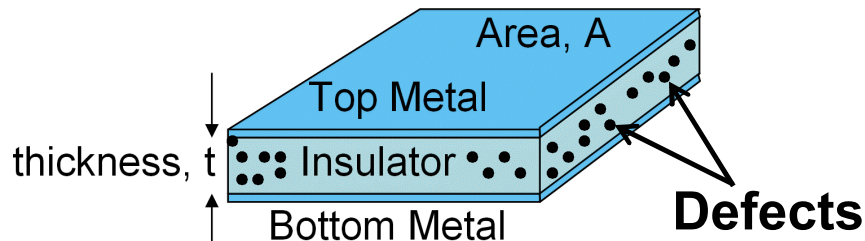


# What are Memristors Really?

- A tantalum oxide metal-oxide-metal sandwich



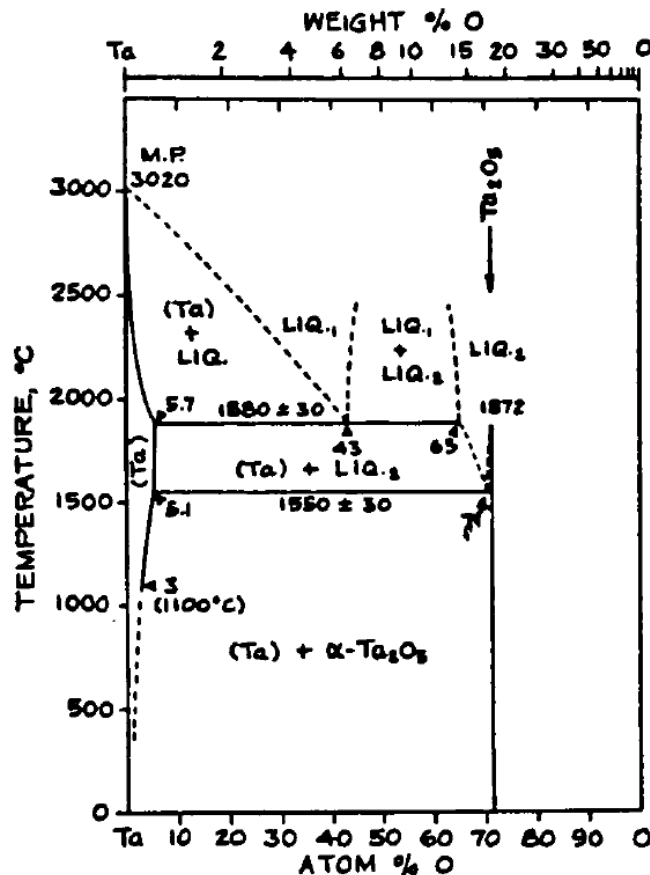
- Good oxides are bad memristors



# Making Bad Oxides is Hard

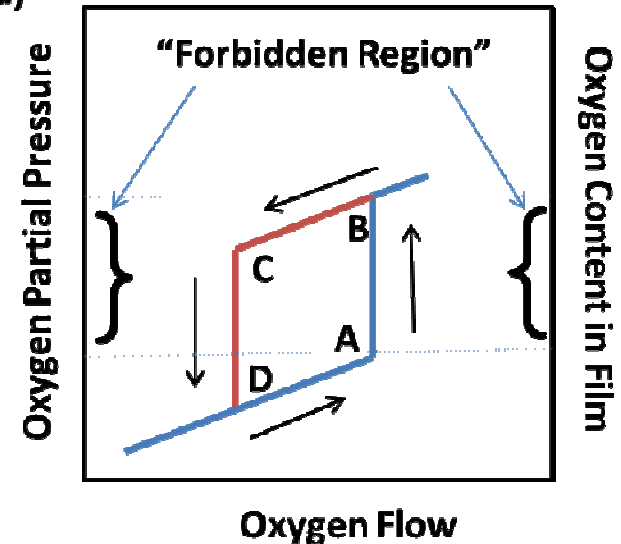
- Making bad oxides is harder than it sounds

- Tantalum Oxide wants to be either Ta or Ta<sub>2</sub>O<sub>5</sub>



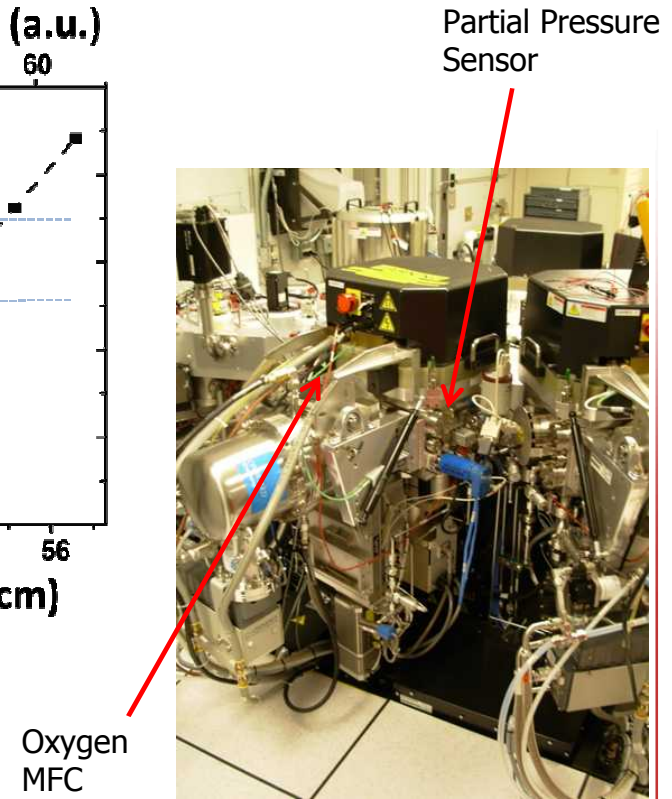
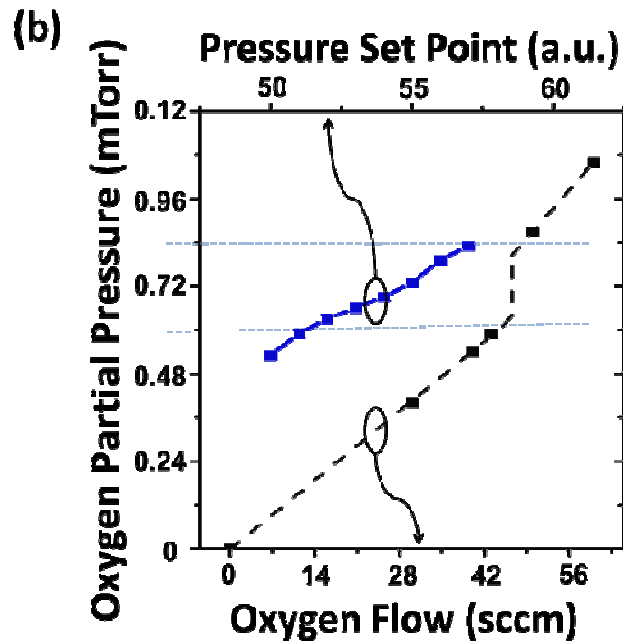
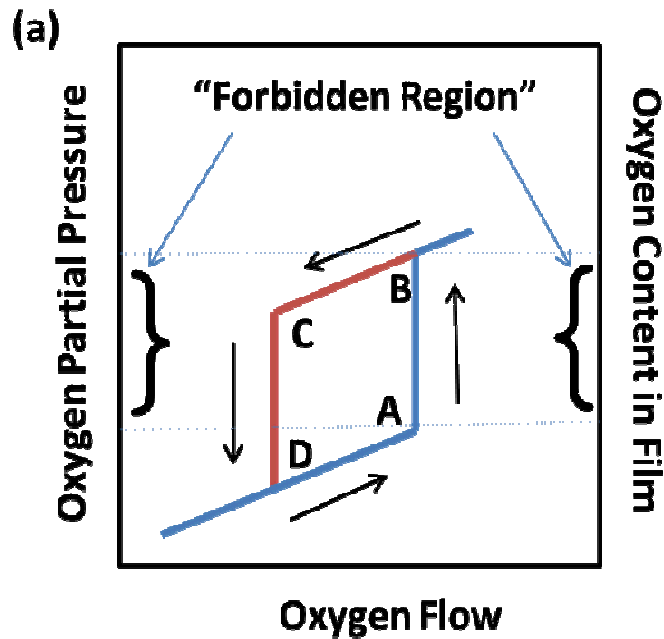
- Sputtering wants to deposit Ta or Ta<sub>2</sub>O<sub>5</sub>

(a)



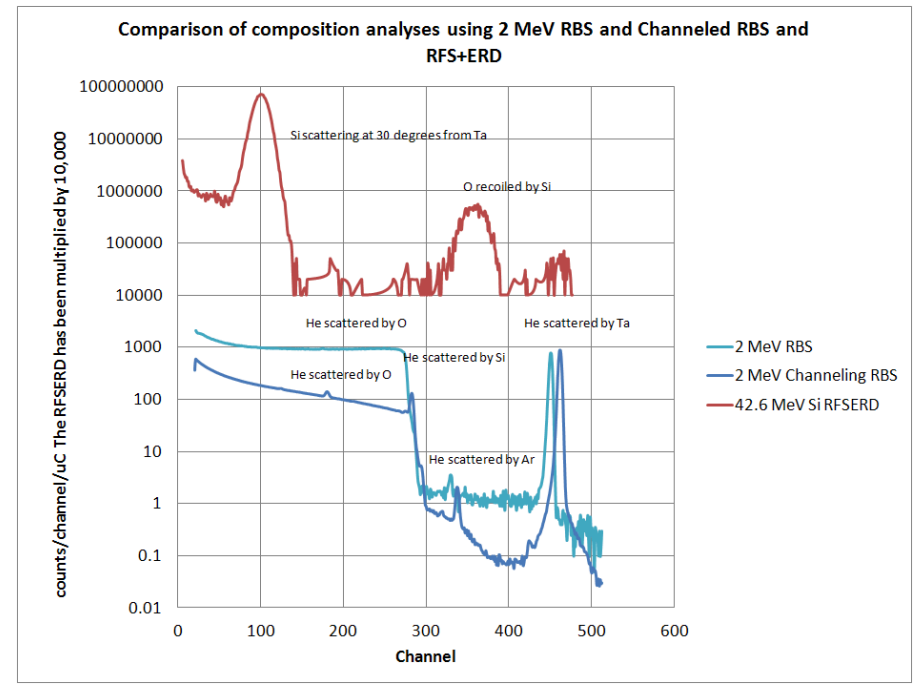
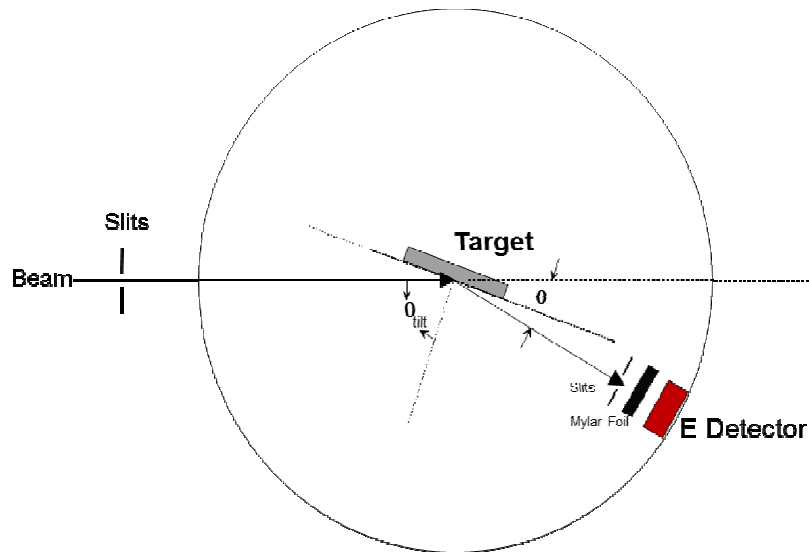
# Making Bad Oxides is Hard

- But it can be done



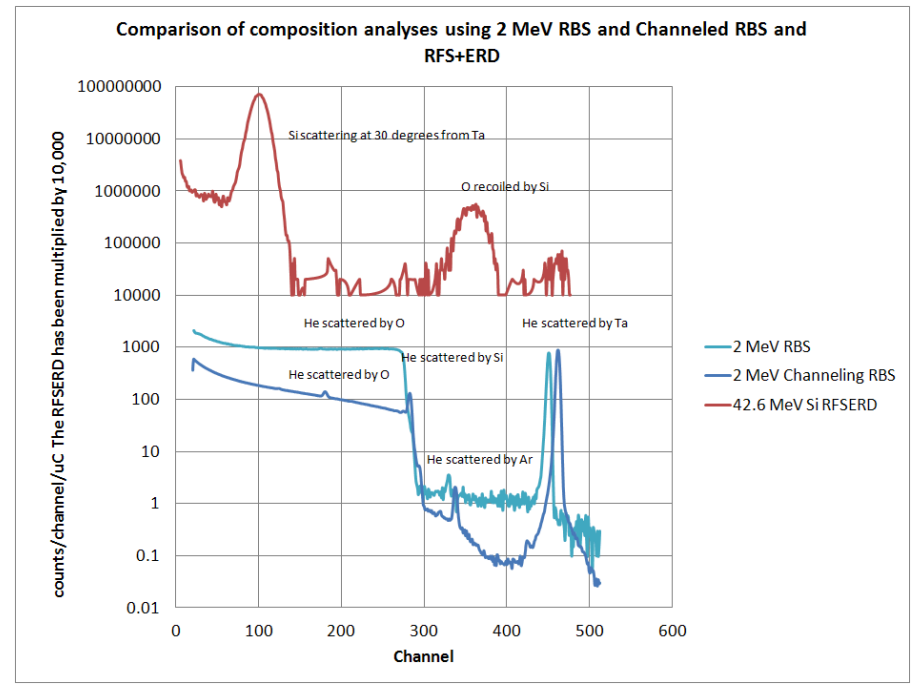
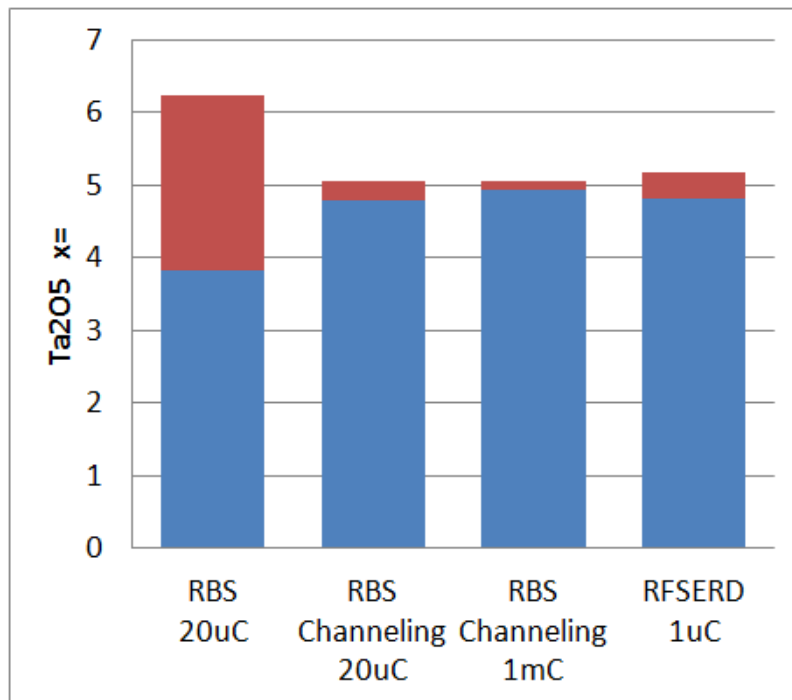
# Calibrating Stoichiometry

- Measuring stoichiometry is challenging too
- Rutherford backscattering won't work!
- Developed a new characterization technique called RFSEERD (Rutherford Forward Scattering and Elastic Recoil Detection).



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# HAXPES

- Measure stoichiometry at varying depths
- Gives chemical bonding state as well as stoichiometry

$$\lambda = E / \{ E_p^2 [\beta \ln(\gamma E) - (C/E) + (D/E^2)] \}$$

$$\beta = -0.0216 + 0.944 / (E_p^2 + E_g^2)^{1/2} + 7.39 \times 10^{-4} \rho$$

$$\gamma = 0.191 \rho^{-0.50}$$

$$C = 1.97 - 0.91U$$

$$D = 53.4 - 20.8U$$

$$U = N_v \rho / M$$

HAXPES Stack

TaOx (15 nm)
Ta or TiN (50 nm)
Si (substrate)

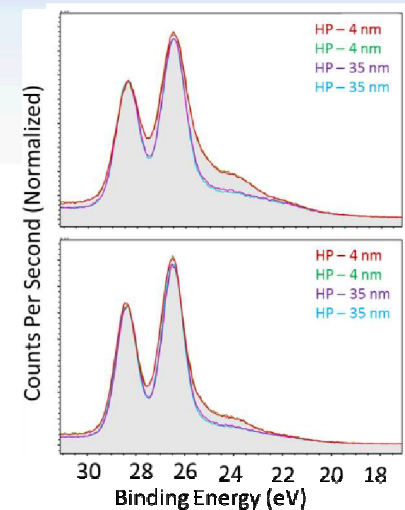
Typical Device Stack

TiN (50 nm)
Ta (50 nm)
TaOx (15 nm)
TiN
Si (substrate)

# HAXPES

- Films made at Sandia are qualitatively different
- Depth and electrode dependence

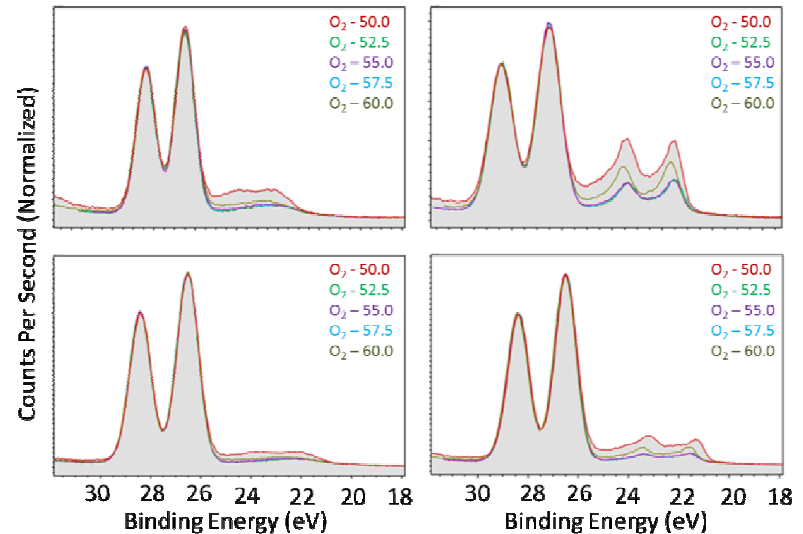
Collaborator Films



Sandia Films

TiN Bottom

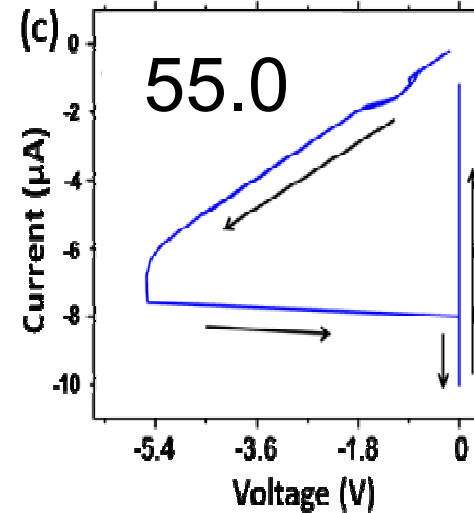
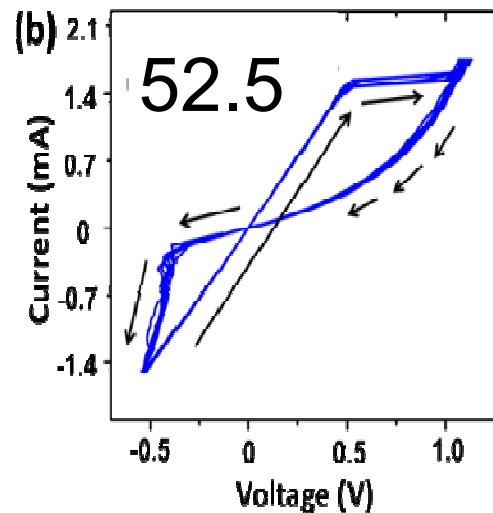
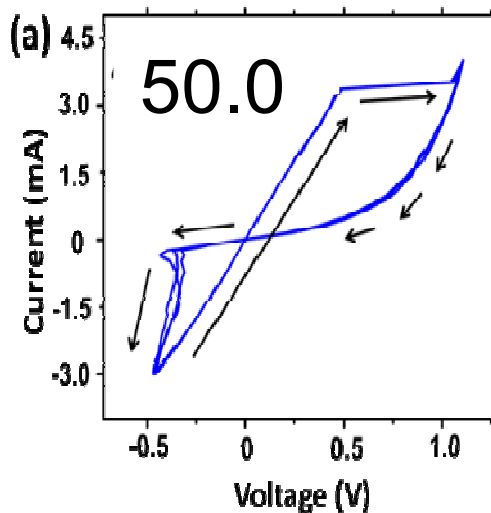
Ta Bottom



# Sandia-Made Devices

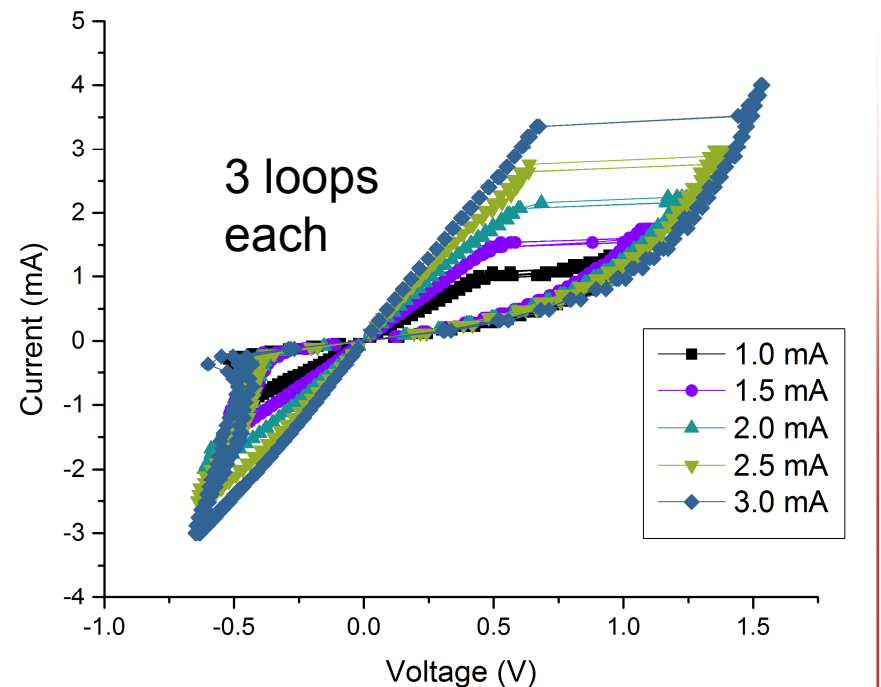
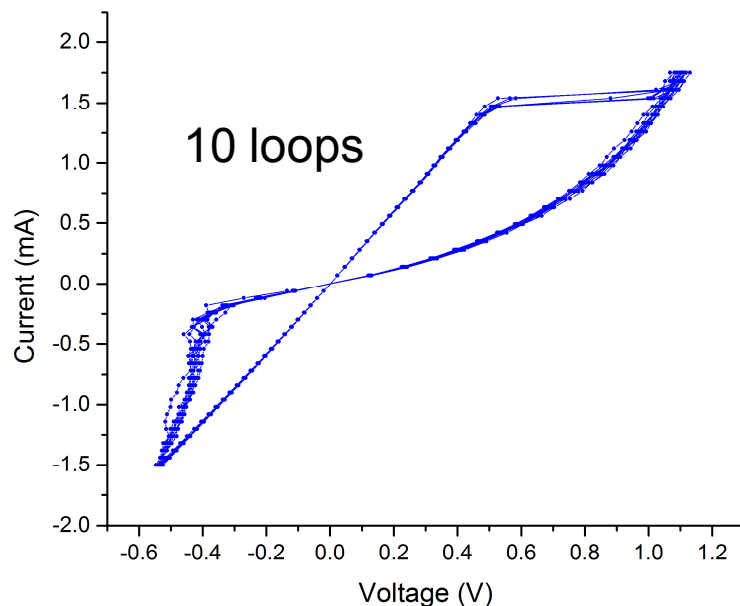
- Low oxygen flows gave forming free, low yield
- High oxygen flows gave devices that shorted easily
- Middle results best
  - Forming free
  - High yield

Partial Pressure Set	x: Ta <sub>2</sub> O <sub>x</sub>	Working Devices?
50.0	$1.9 \pm 0.5$	Some
52.5	$3.3 \pm 0.5$	Yes
55.0	$4.2 \pm 0.5$	No
57.5	$4.6 \pm 0.5$	No
60.0	$5.0 \pm 0.5$	No



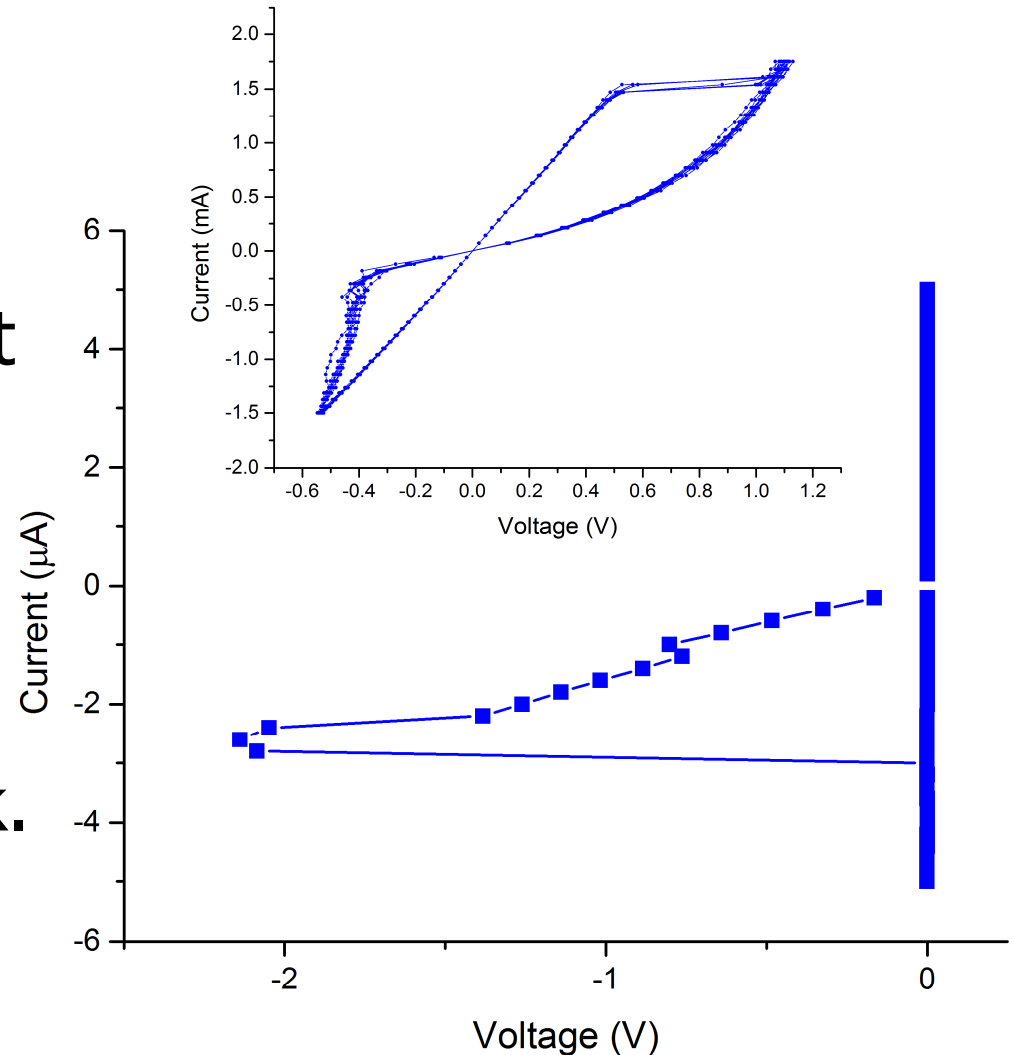
# Sandia-Made Devices

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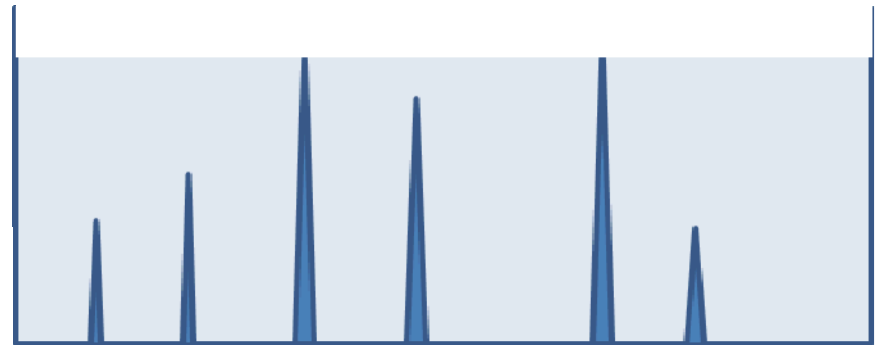
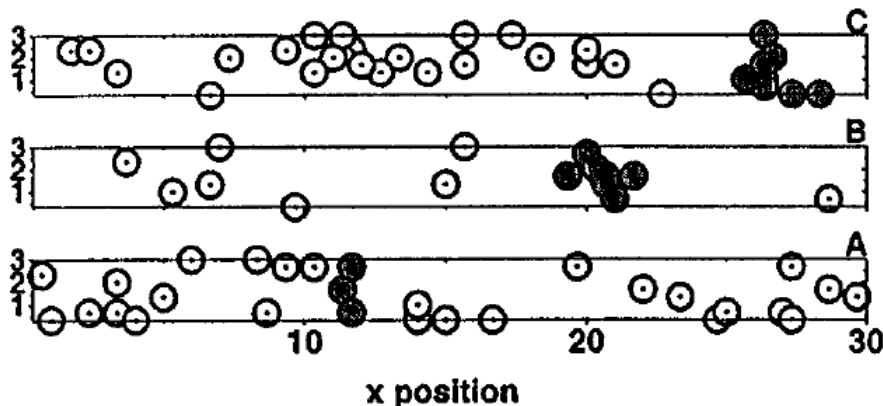
# Annealing?

- Strange Reverse Forming Required
- Most likely the effect is some sort of anneal
- Possibly the filament is extended with negative feedback.



# Possible Structure/Mechanism

- Possibly the OFF current anneals the device with negative feedback.
- Hard breakdown of thick oxides vs soft for thin



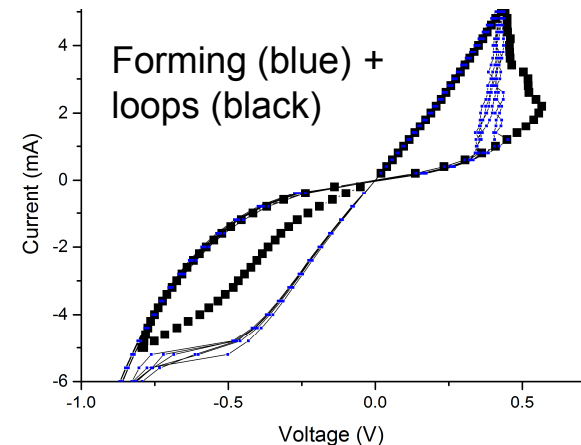
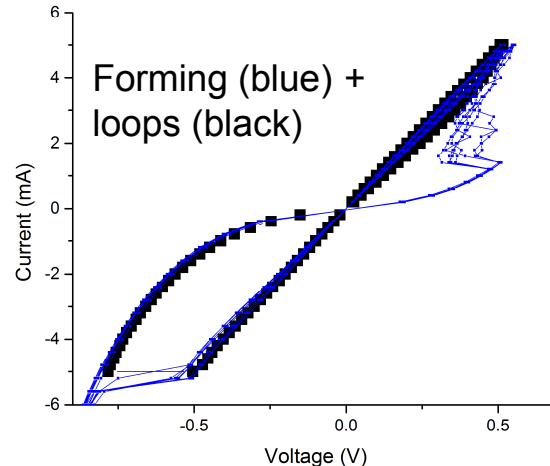
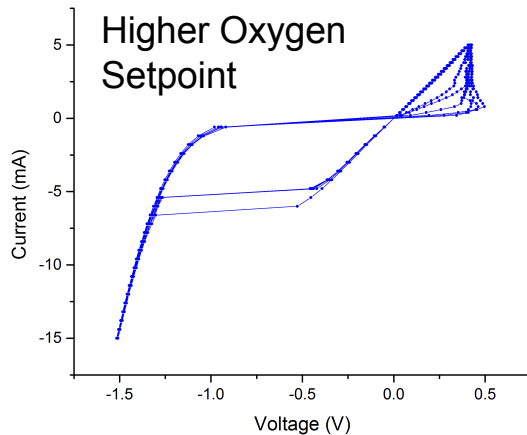
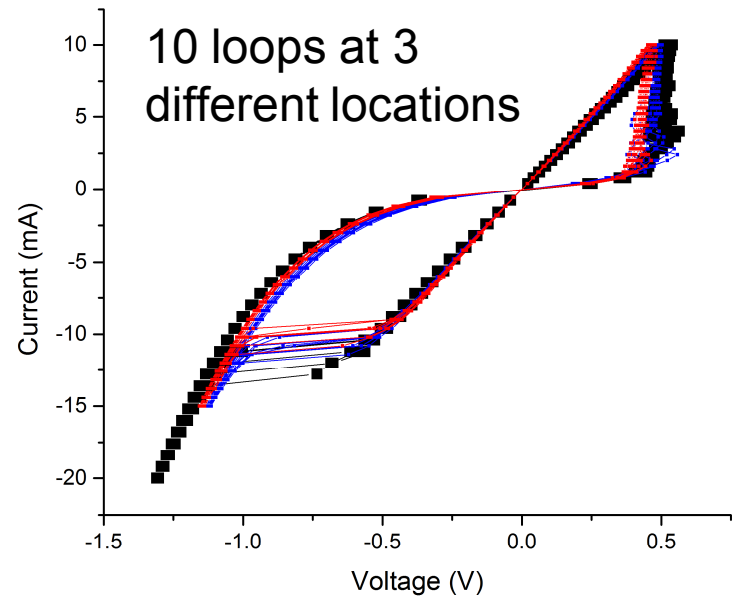


# Summary

- We have developed a forming free memristor process
  - Process gives increased reproducibility
  - Papers to come soon
- We developed a new ion beam technique to characterize the films
- We learned about the chemical bonding and gradients in the films
- We are gaining insight into the forming and switching process

# MicroFab Dot Caps

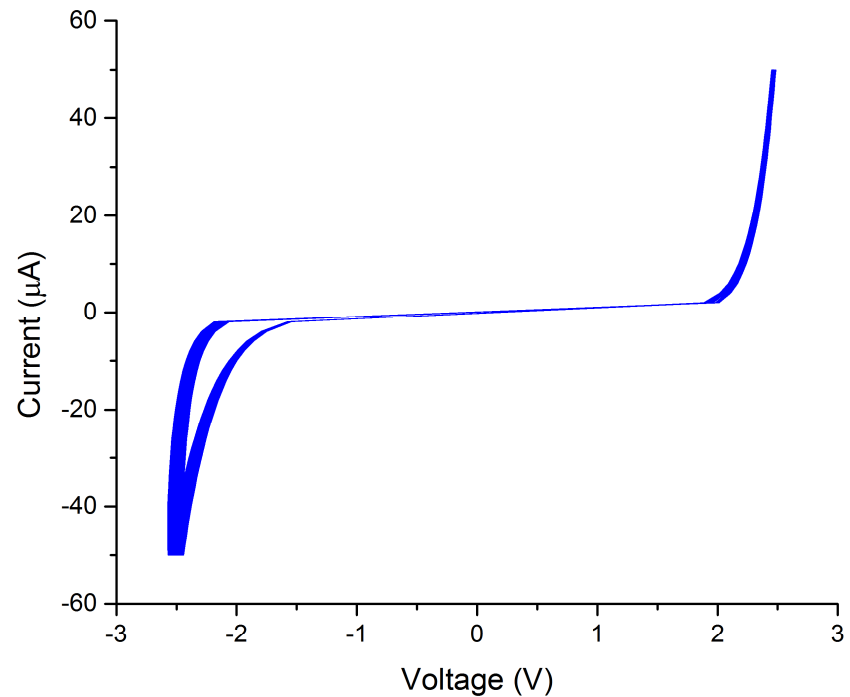
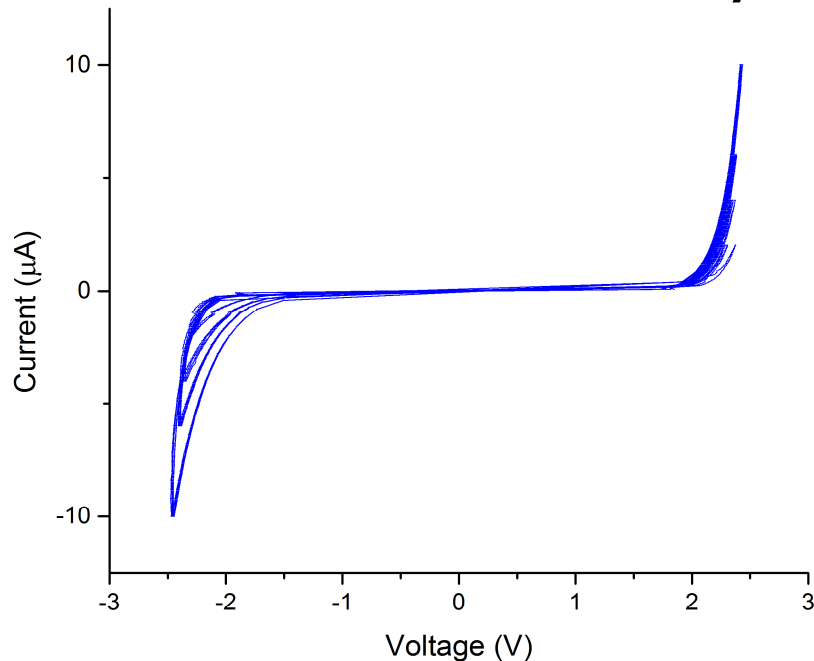
- Microfab Memristors
- Truly forming free
- Control On/Off ratio
- Consistency!
- Reproducibility?





# More MicroFab Dot Caps

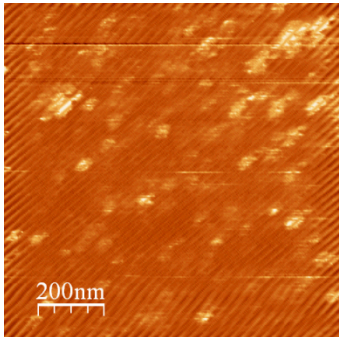
- Highly Nonlinear
- High Resistance
- Forming Free
- Good Consistency



# Hot Spot Mapping

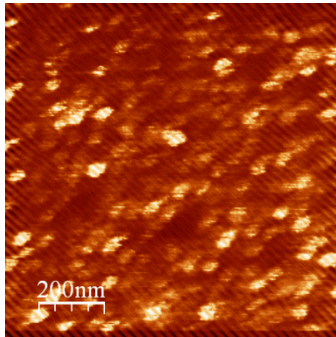
- Localized hot spots exist in the films suggesting the spire model is likely.

Vtip=2.4 V



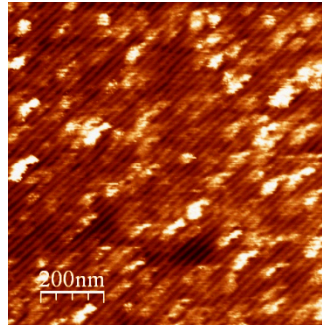
20120806\_swh-16-  
38\_TaOx-CAFM\_0008

Vtip=2.6 V



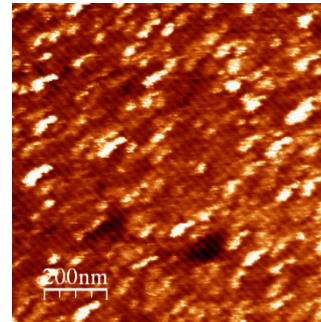
20120806\_swh-16-  
38\_TaOx-CAFM\_0009

Vtip=2.8 V



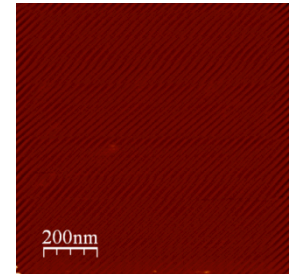
20120806\_swh-16-  
38\_TaOx-CAFM\_0010

Vtip=3.0 V



20120806\_swh-16-  
38\_TaOx-CAFM\_0011

Vtip=2.0 V



20120806\_swh-16-  
38\_TaOx-CAFM\_0012

Preamp Gain =  $10^9$  V/A  
Same spot imaged with increasing tip  
voltage  
Brighter colors indicate more conduction

